

1775

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of **Steinb rg**

Application No. 10076858

Attorney Docket No. Shipley 03-19; DN: 51969 (Act - 183/184)

Filed: February 14, 2002

For: MICROMACHINED STRUCTURES
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NOV 24 2003

TC 1700

Examiner: Stephen J. Stein

Group Art Unit: 1775

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8(a)

I hereby certify that this Correspondence is being deposited on the date identified below with the United States Postal Service as first-class mail in an envelope properly addressed to Commissioner for Patents, Alexandria, VA 22313-1450.

11-12-2003
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Cristin Donahue
Cristin Donahue

Commissioner for Patents
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.97**

In compliance with the duty of disclosure set forth in 37 C.F.R. § 1.56, Applicants are submitting herewith a Form PTO-1449 and a copy of the references listed thereon. This Information Disclosure Statement is being filed more than three months after the filing date of the application. However, Applicants have not yet received an action on the merits of the application. Accordingly, Applicants believe that no fee is required pursuant to 37 C.F.R. § 1.97 (b) (3). In the event a fee is required, the Commissioner is authorized to charge the required fees to deposit account no. 04-1406. A duplicate copy of this sheet is included for fee processing, if necessary.

Applicants respectfully request full and proper consideration of the listed

information during examination of the application, and that the listed information be printed on any patent that issues therefrom.

Respectfully submitted,

DANN, DORFMAN, HERRELL & SKILLMAN
A Professional Corporation
Attorneys for Applicant(s)

By



Niels Haun

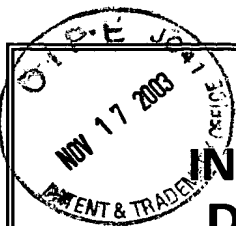
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Enclosures - Form PTO-1449

Copies of references listed on PTO - 1449



INFORMATION DISCLOSURE STATEMENT

SHEET 1 OF 1

Complete if known

Application Number: 10076858

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First Named Inventor: Steinberg

TC 1700

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Examiner Name: Stephen J. Stein

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UNITED STATES PATENT DOCUMENTS

| EXAMINER'S INITIALS | CITE NO. | PATENT NUMBER | ISSUE DATE MM-DD-YYYY | FIRST NAMED INVENTOR |
|------------------------|-------------|---------------|--------------------------|----------------------|
| | | | | |

FOREIGN PATENT DOCUMENTS

| EXAMINER'S INITIALS | CITE NO. | DOCUMENT NUMBER | COUNTRY OR REGION | DATE OF PUBLICATION MM-DD-YYYY | FIRST NAMED INVENTOR OR APPLICANT |
|------------------------|-------------|--------------------|----------------------|--------------------------------------|--------------------------------------|
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OTHER PRIOR ART - NON-PATENT DOCUMENTS

| EXAMINER'S INITIALS | CITE NO. | Include name of the author (in Capital Letters), title of the article (when appropriate), title of the item(book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published |
|------------------------|-------------|---|
| | | J. G. Fleming, "Combining the best of bulk and surface micromachining using Si {111} substrates." SPIE Vol. 3511, September 1998, pp. 162-168. |
| | | J. Brugger, et al., "Self-aligned 3D shadow mask technique for patterning deeply recessed surfaces of micro-electro-mechanical systems devices." Sensors and Actuators 76 (1999) pp. 329-334. |

| EXAMINER'S SIGNATURE | DATE CONSIDERED |
|-------------------------|--------------------|
| | |

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP §609. Draw a line through citation if citation not in conformance and reference not considered. Include a copy of this form with next communication to applicant.